

# Microweekly 43

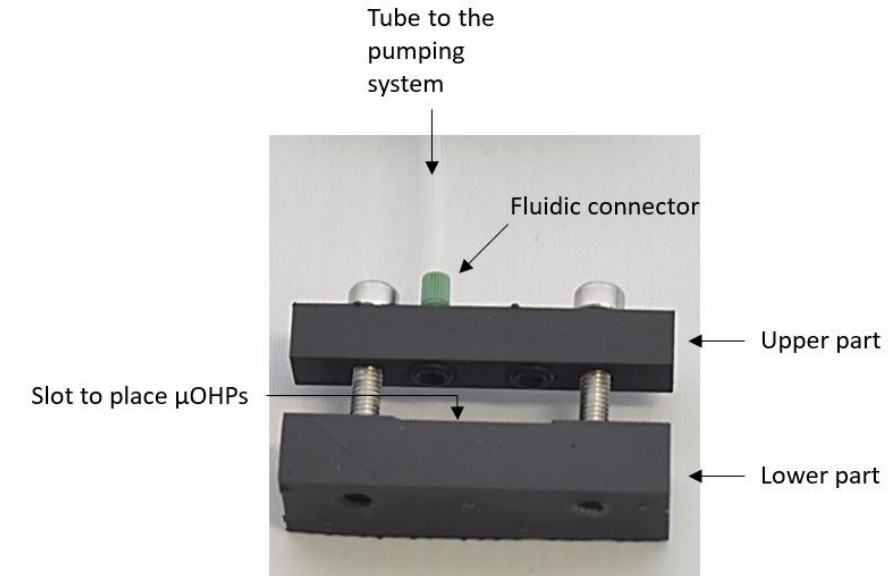
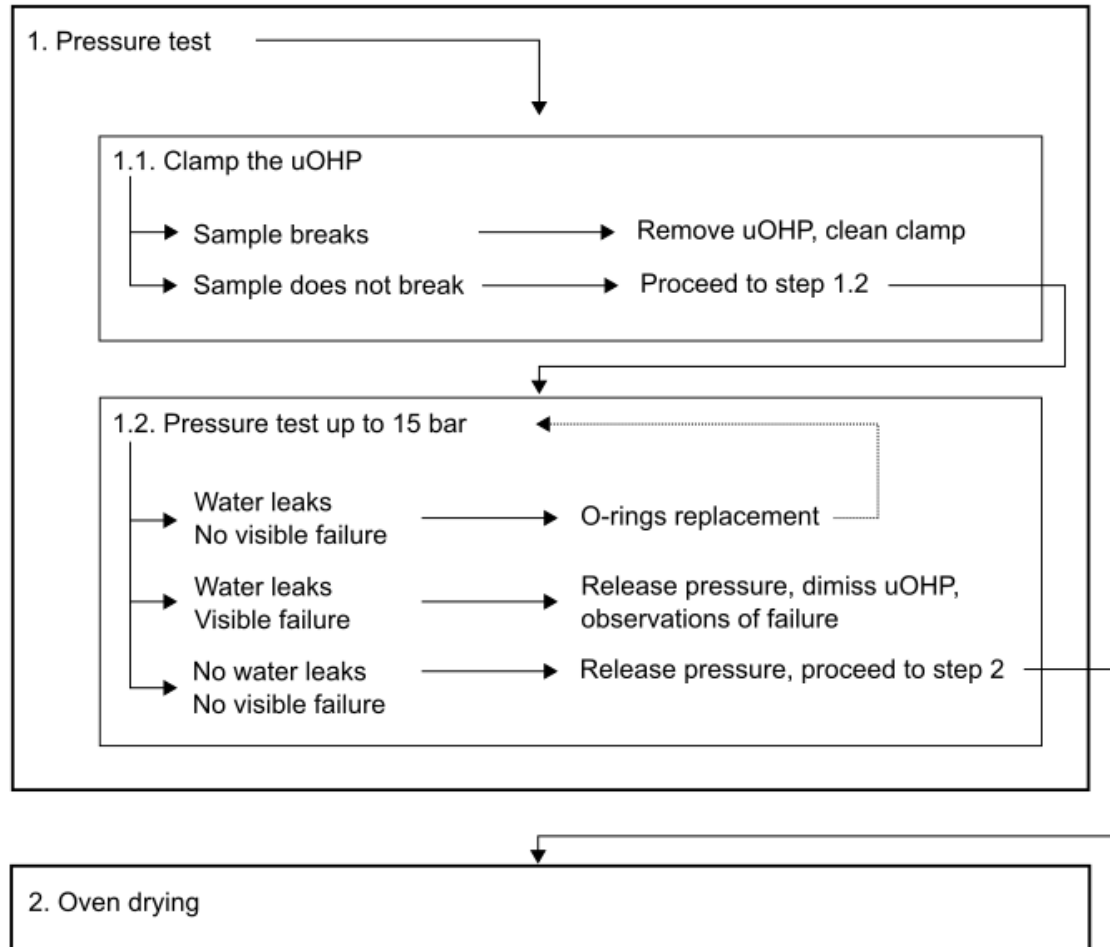
Timothée Frei

26.10.2018



# Low pressure test for quality control of $\mu$ OHPs

## Procedure



# Low pressure test for quality control of $\mu$ OHPs

## Trials with dummies

Mounting, applying 15bar of pressure and dismounting:

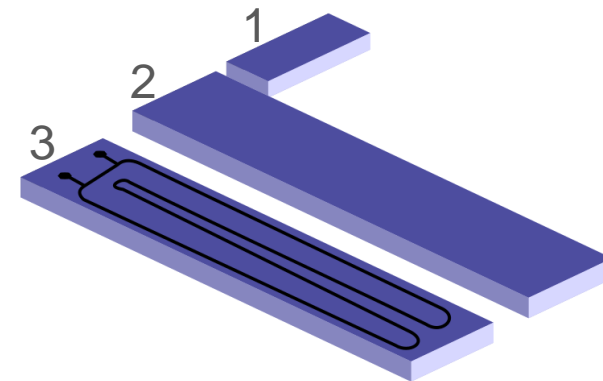
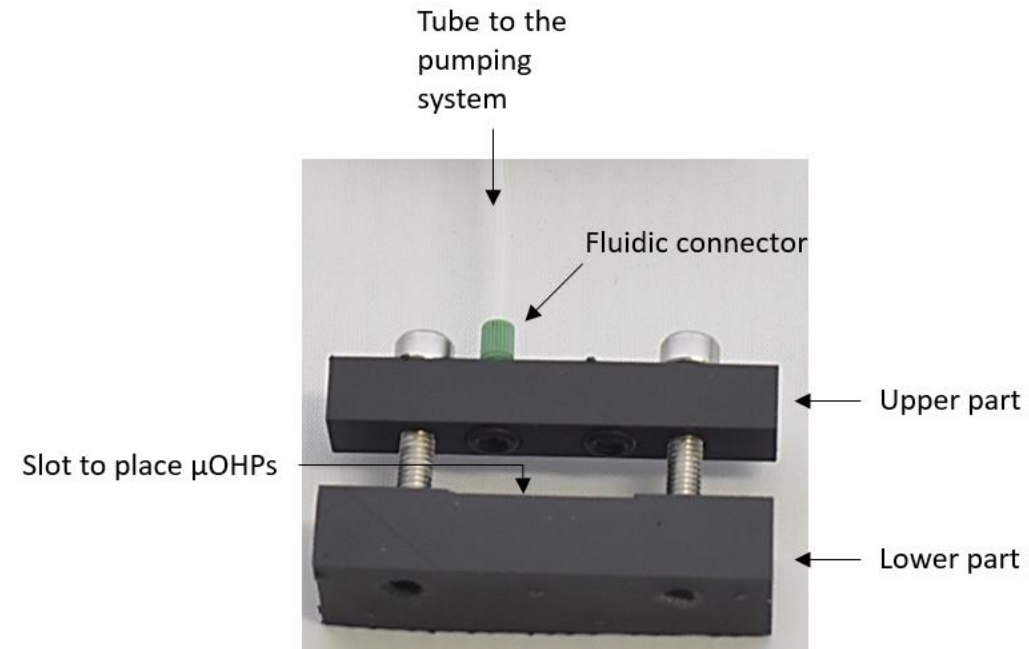
1. Use short dummies (10mmx20mm)
2. Use long dummies (100mmx20mm)

## Then with $\mu$ OHPs

After getting used to manipulations:

3. Use  $\mu$ OHPs to perform the quality control

In the end, the QC procedure will give the 'GO' or 'NO GO' to further process the wafers (bonding and metal deposition)

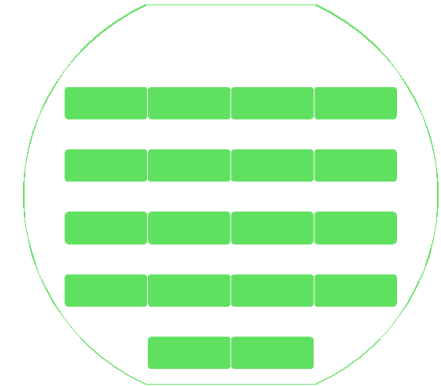


# TiW deposition with shadow masks

---

## Masks ordered at CERN Store - Raw material (waterjet cutting)

CERN stores delivery date: today



## Planning for deposition

31.10 – End of deposition of Cu at CSEM + TiW target put in place

01.11 – Deposition of TiW (sputtering) on glass wafer